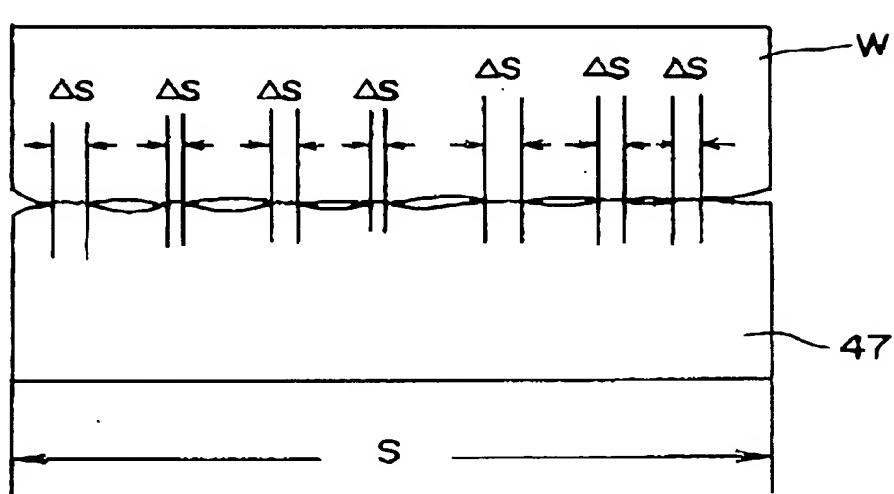


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Fig.1



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Fig.2

Temperature Distribution in Wafer Surface
in Device Process Chamber

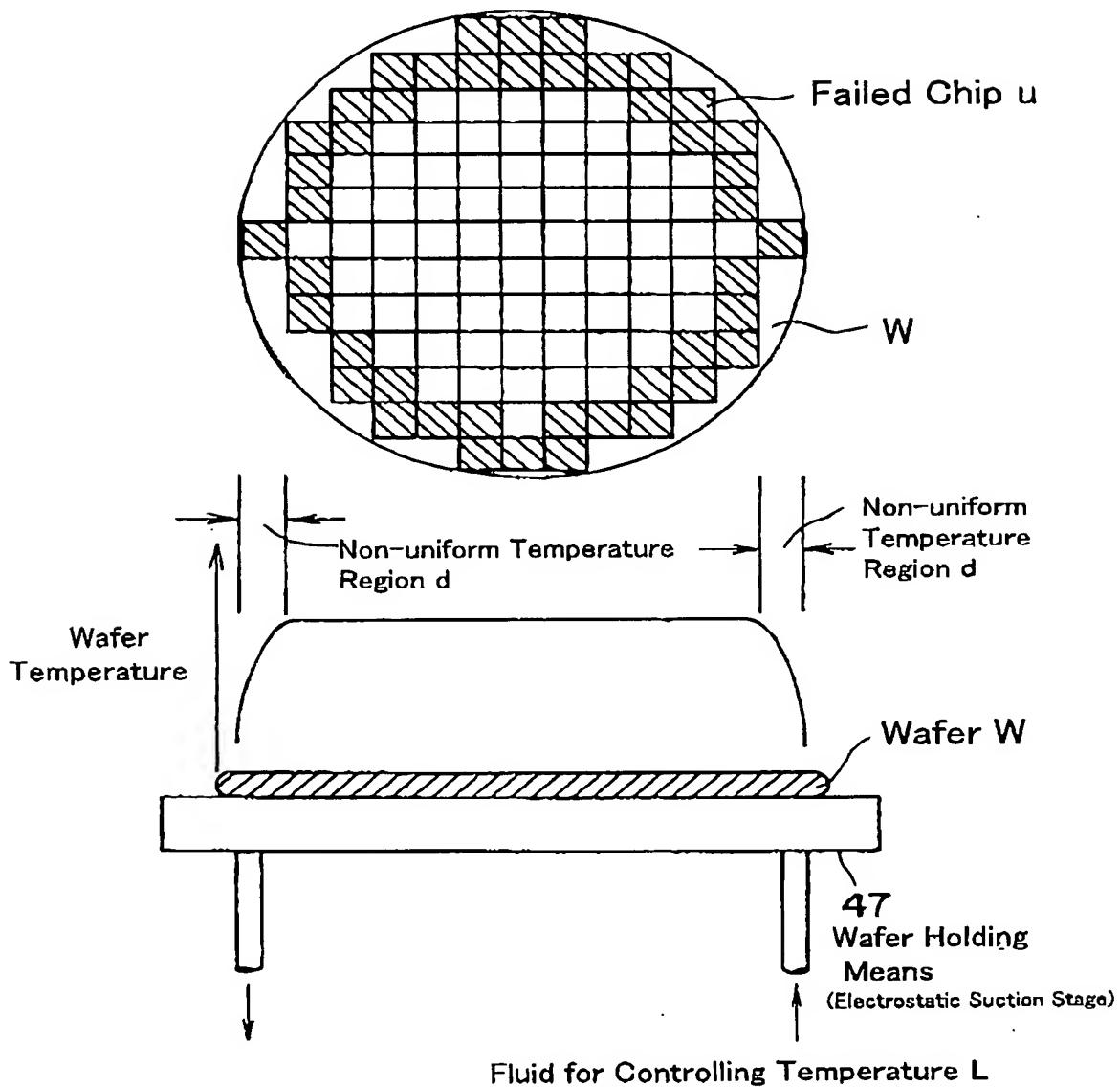


Fig 3.(A)

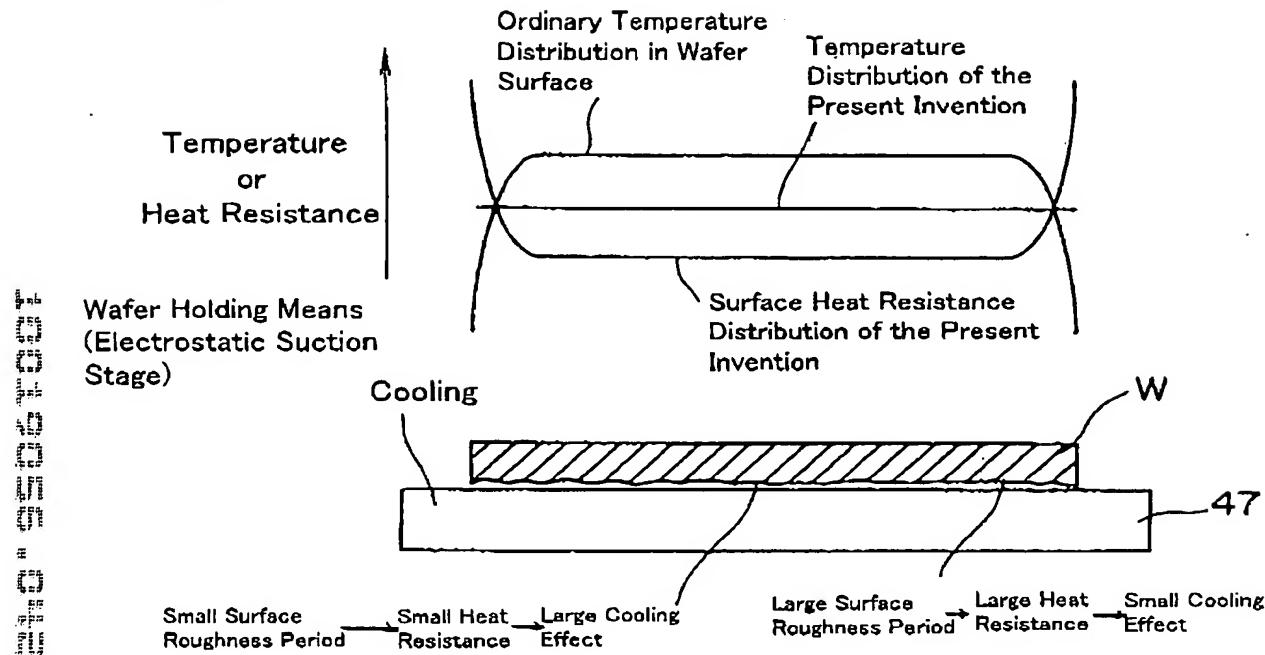
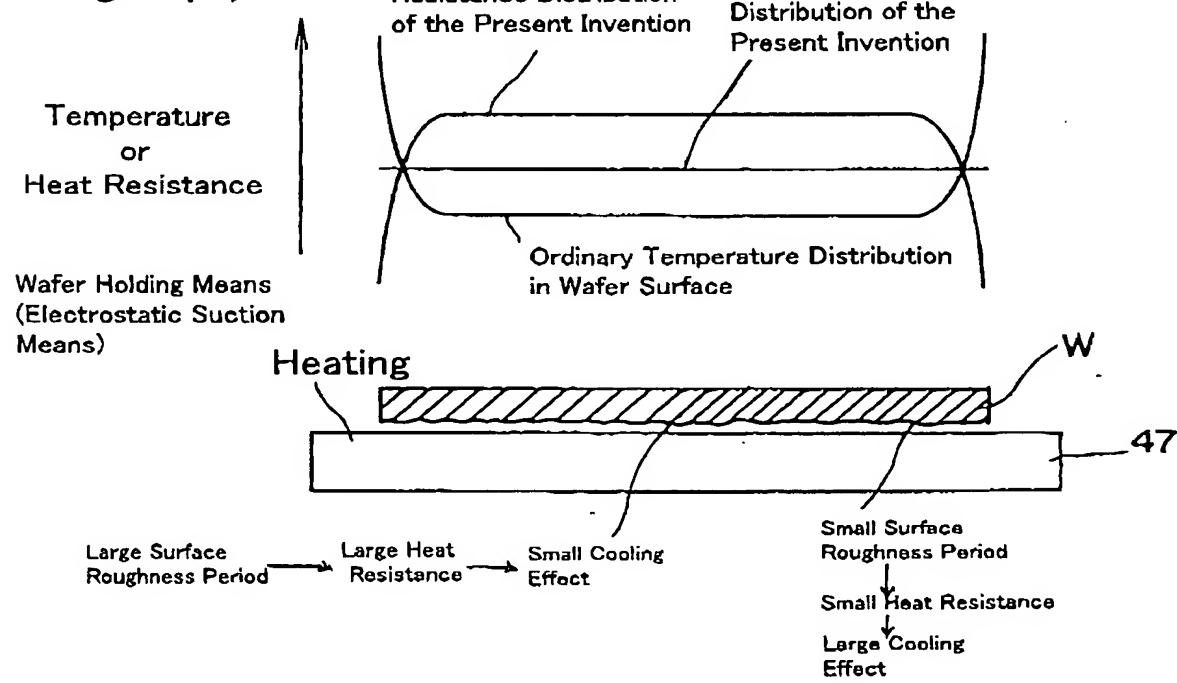


Fig 3.(B)



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Fig.4

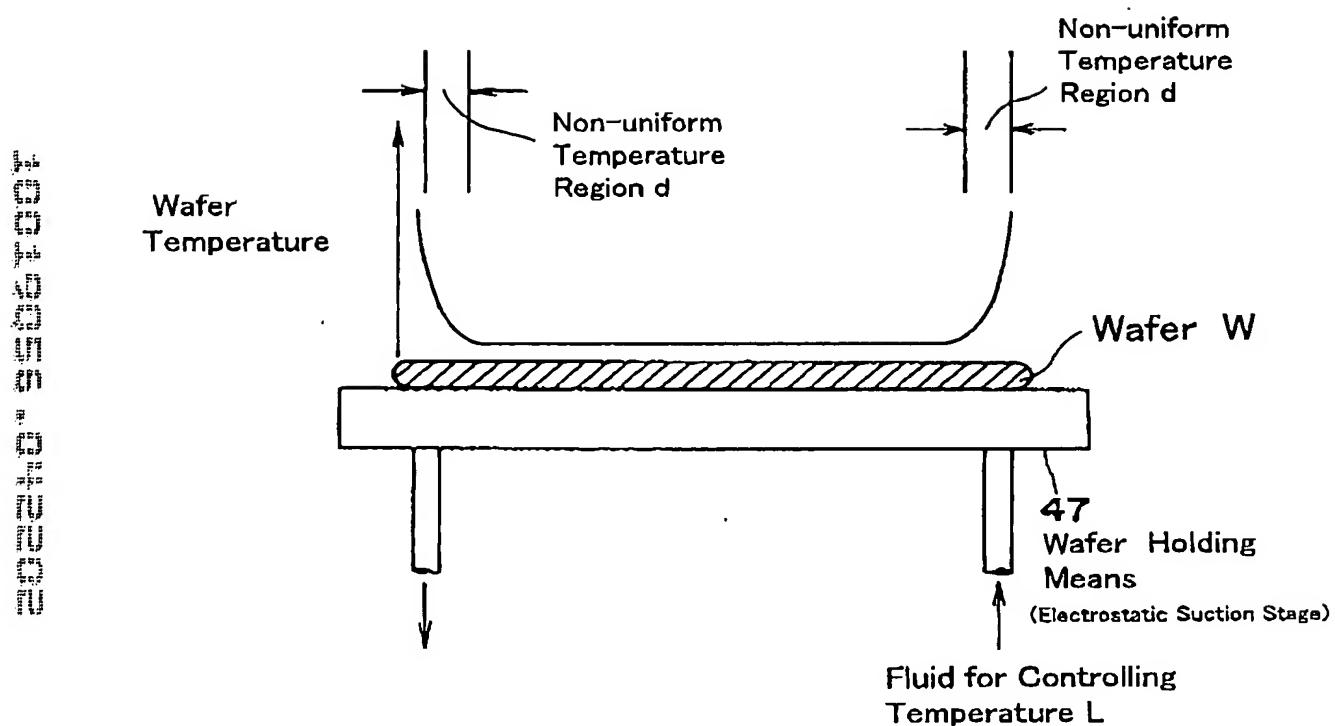
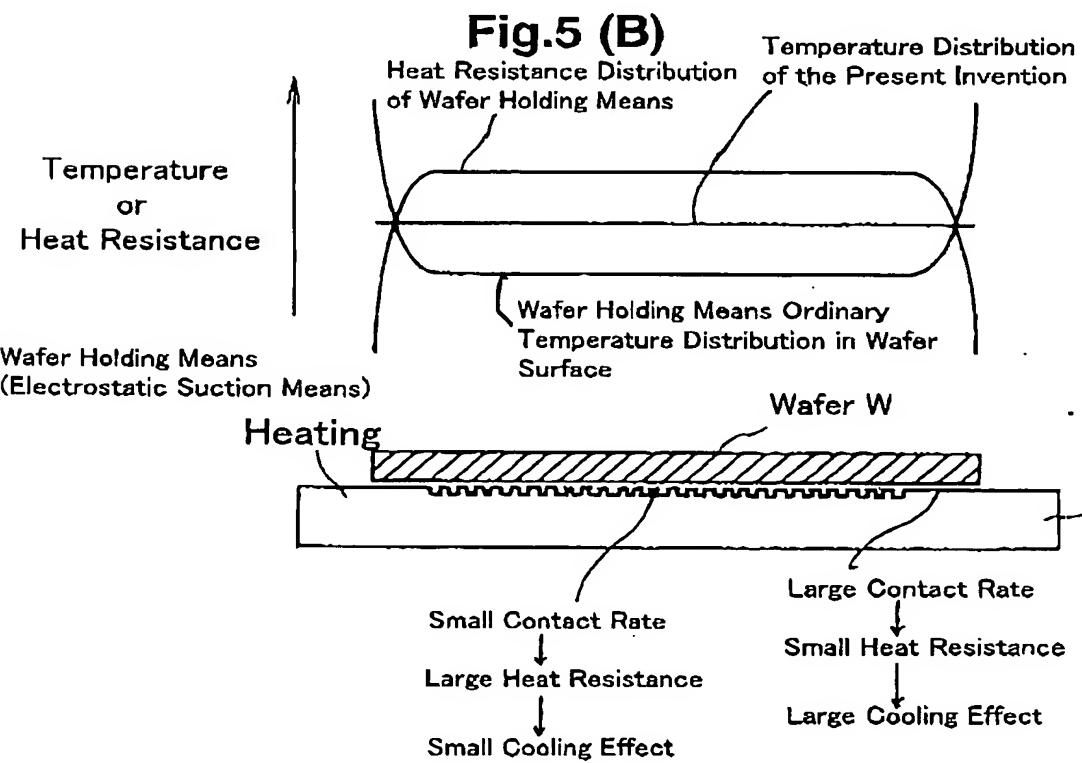
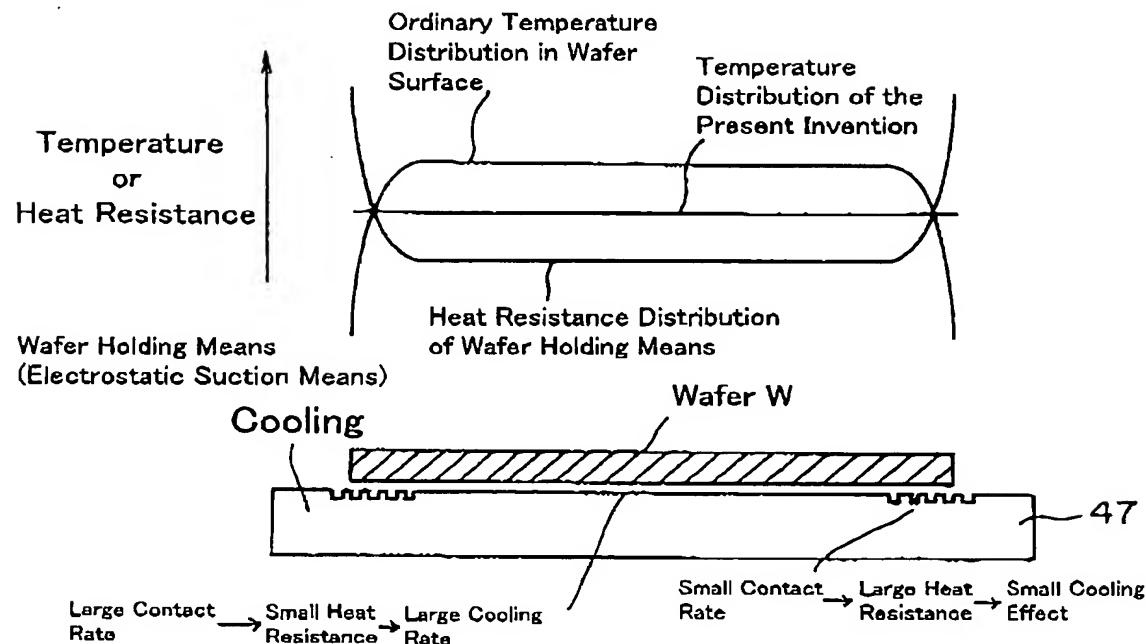
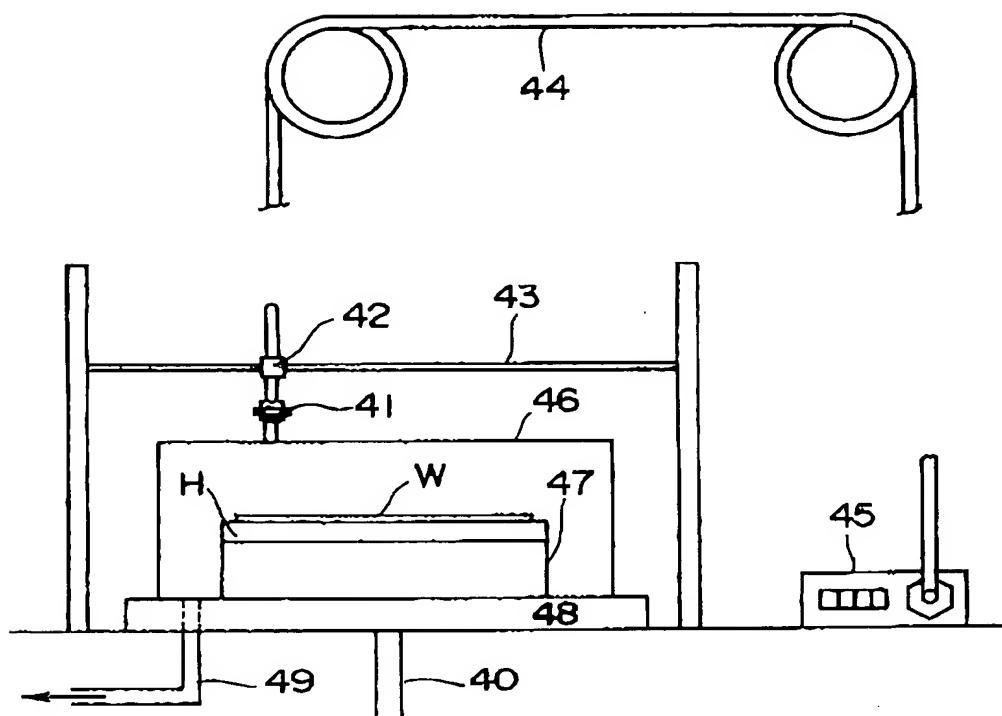
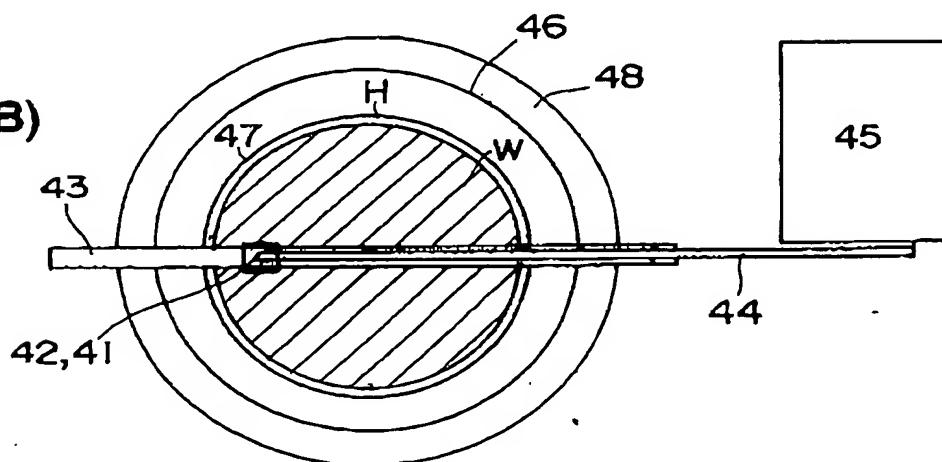


Fig.5 (A)



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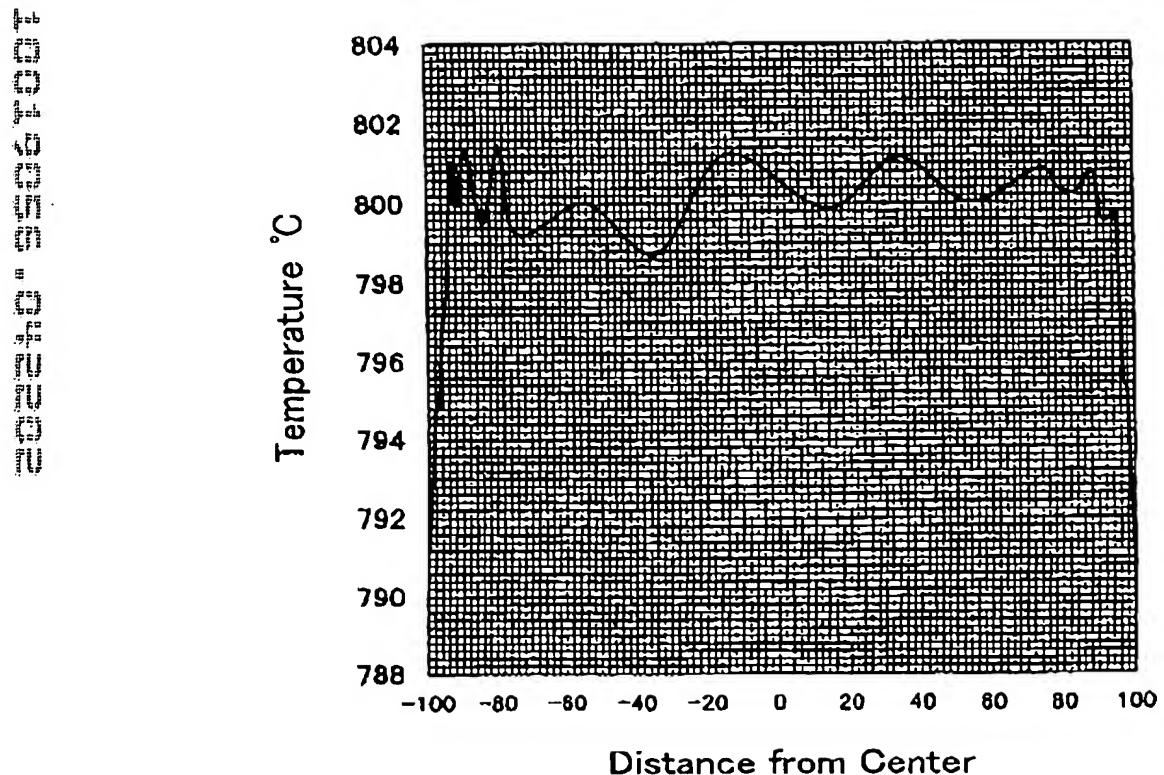
Fig.6 (A)**Fig.6 (B)**

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Fig.7

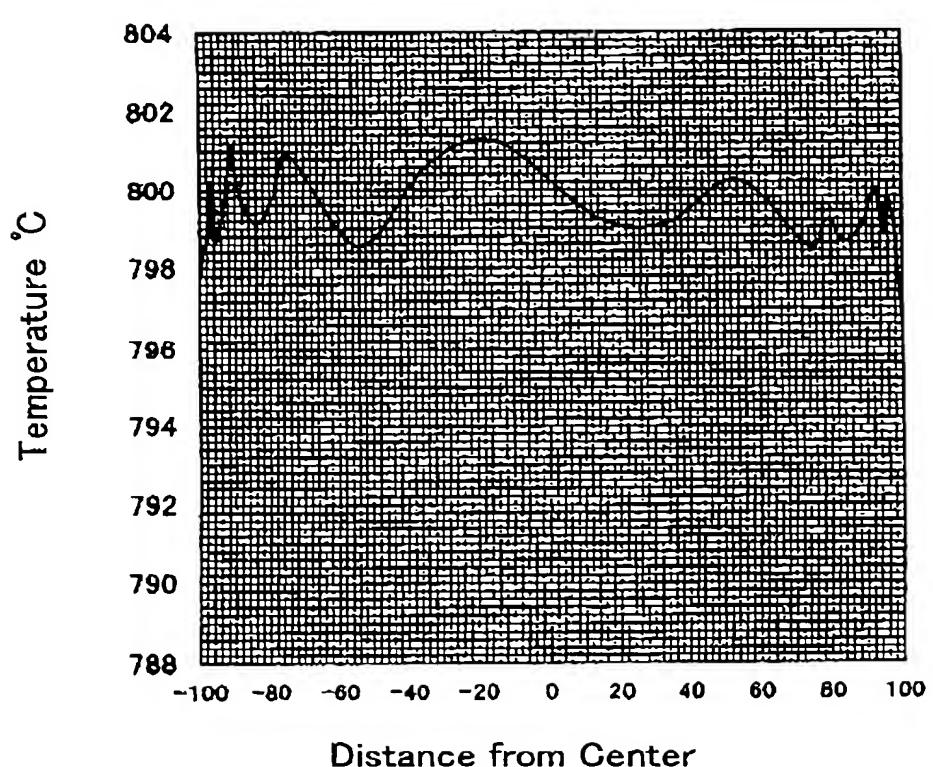
**Temperature Distribution in Wafer Surface
Comparative Example**



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Fig.8

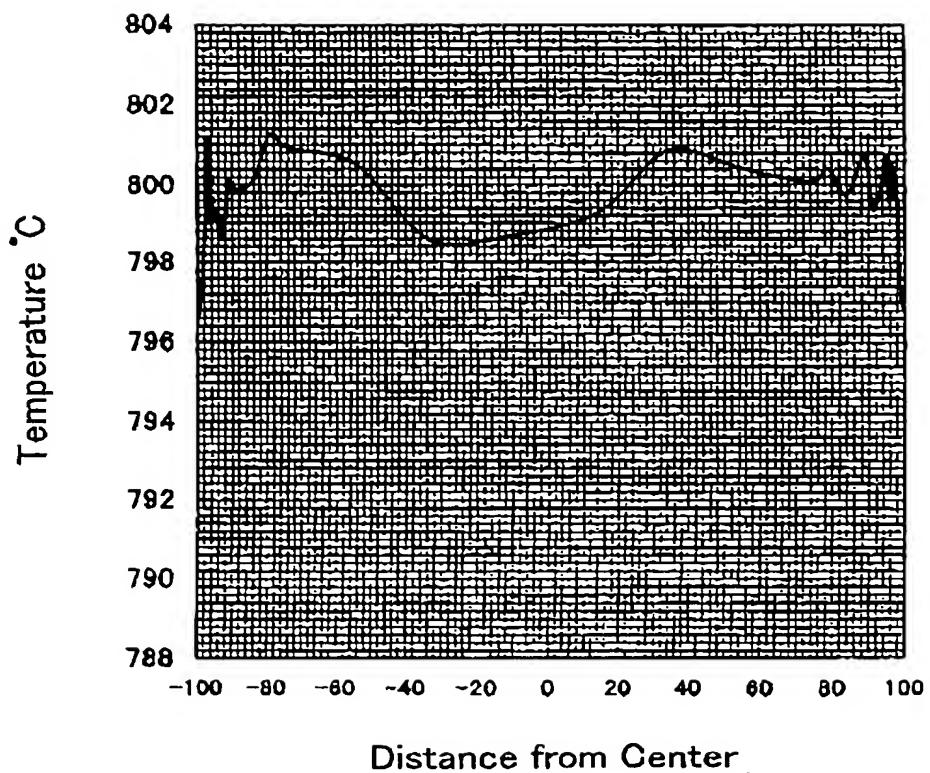
Temperature Distribution in Wafer Surface
Example 1



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Fig.9

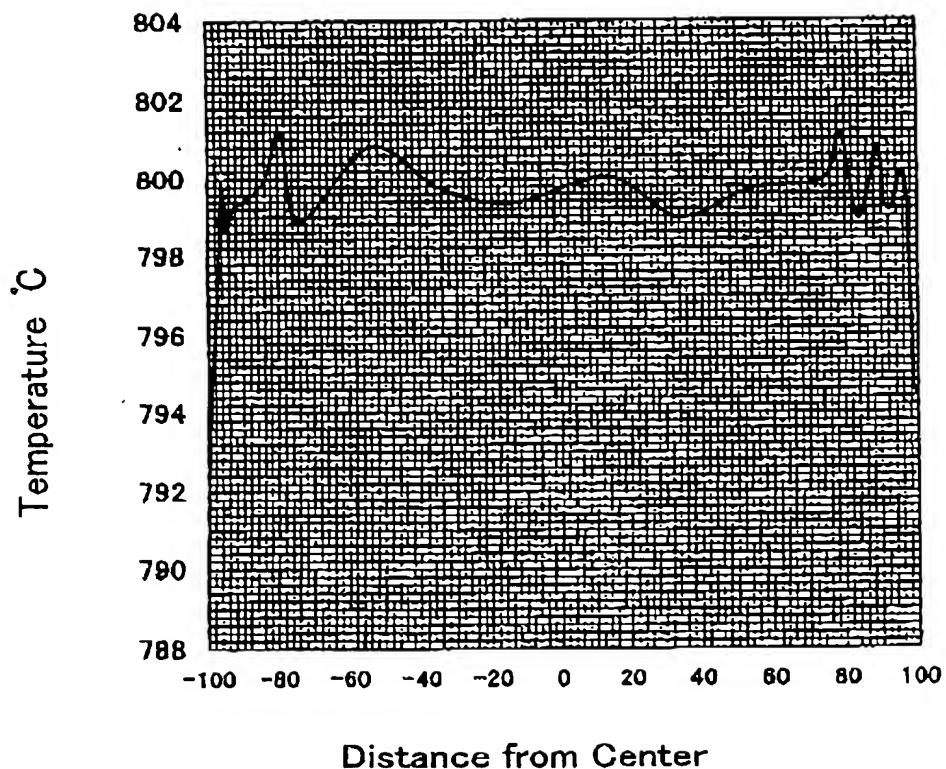
Temperature Distribution in Wafer Surface
Example 2



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Fig.10

Temperature Distribution in Wafer Surface
Example 3



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Fig.11

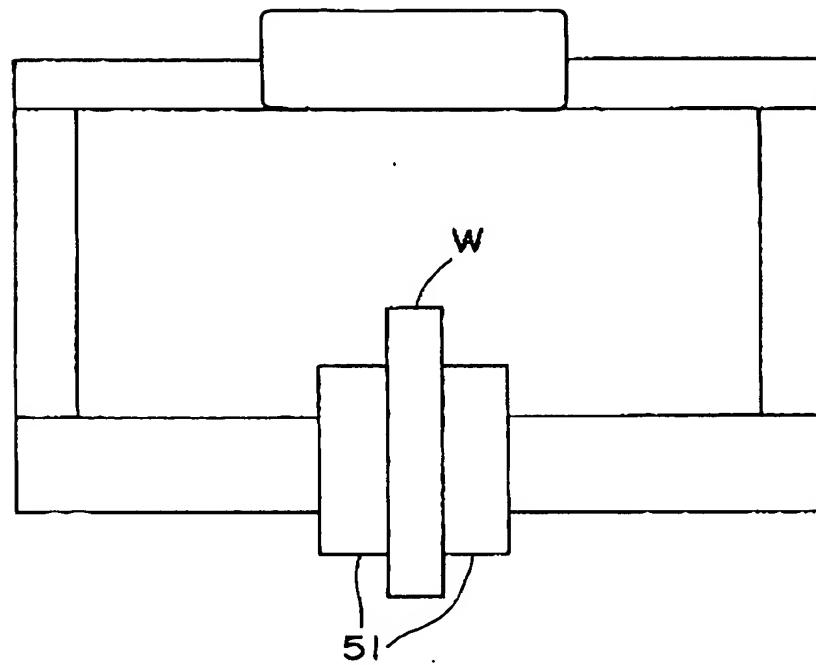


Fig.12

